



PATENT
Attorney Docket No. 02887.0257-00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
)	
Akira HAMAGUCHI <i>et. al.</i>)	Group Art Unit: 2624
)	
Application No.: 10/687,828)	Examiner: Vikkram BALI
)	
Filed: October 20, 2003)	Confirmation No.: 2967
)	
For: METHOD AND APPARATUS FOR)	
DETERMINING DEFECT)	
DETECTION SENSITIVITY DATA,)	
CONTROL METHOD OF DEFECT)	
DETECTION APPARATUS, AND)	
METHOD AND APPARATUS FOR)	
DETECTING DEFECT OF)	
SEMICONDUCTOR DEVICES)	

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

REPLY TO OFFICE ACTION

In reply to the Office Action mailed January 25, 2007, the period for response having been extended to July 25, 2007 by a request for extension of three months and fee payment filed concurrently herewith, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims in this paper.

Remarks/Arguments follow the amendment sections of this paper.